



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Min-Lung HUANG et al. Confirmation No: 8687
Appl. No. : 10/820,855
Filed : April 9, 2004
Title : Under Bump Metallization Structure Of A Semiconductor Wafer

TC/A.U. : 2813
Examiner : D. S. Blum

Docket No.: HUAN3262/REF
Customer No: 23364

AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

This is in response to the Official Action of April 11, 2006, in connection with the above-identified application. The period for response to the Official Action has been extended to expire on August 11, 2006 by the filing herewith of a Petition for a One Month Extension of Time and payment of the required fees.

Please amend the application as follows:

Amendments to the specification begin on page 2 of this paper.

Amendments to the claims are reflected in the listing of claims which begins on page 5 of this paper.

Remarks begin on page 8 of this paper.